



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re Application of:
Latchford, et al.

Serial No.: 09/921,938

Confirmation No.: 8367

Filed: August 2, 2001

For: Photolithography Scheme Using a
Silicon Containing Resist

Box AF
Assistant Commissioner for Patents
Washington, D.C. 20231

§§§ Group Art Unit: 1752

§§§ Examiner: A. C. Walke

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37 CFR 1.8

I hereby certify that this correspondence is being deposited on
September 6, 2002 with the United States Postal Service as
First Class Mail in an envelope addressed to: Box AF
Commissioner for Patents, Washington, D.C. 20231.

9/6/02
DateKeith M. Tackett
Signature

Dear Sir:

PETITION FOR ONE-MONTH EXTENSION OF TIME

Applicant respectfully petitions the Commissioner under 37 CFR 1.136(a) to grant a one-month extension of time to and including September 6, 2002, in which to file the Response to Final Office Action dated May 6, 2002.

This form is filed in duplicate. The Commissioner is authorized to charge the fee of \$110.00 and any additional fees which may be required for this submission to Deposit Account No. 20-0782/AMAT/4227.P1/DSM/KMT.

Respectfully submitted,

Keith M. Tackett
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